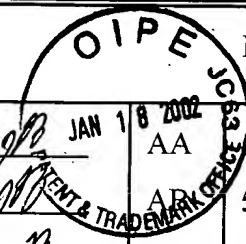


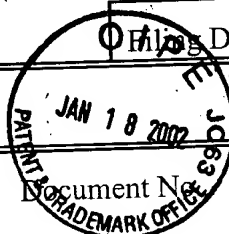
<b>INFORMATION DISCLOSURE CITATION PTO-1449</b>	Atty. Docket No. 010816	Serial No. 09/891,612
	Applicant: Mamoru NAKASUJI et al.	
	Filing Date: June 27, 2001	Group Art Unit:

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		Document No.	Date	Country	Translation (Yes or No)
	AA	52-115161✓	09/27/77	JAPAN	ABSTRACT
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	AF	62-195838✓	08/28/87	JAPAN	ABSTRACT
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	AV	07-249393✓	09/26/95	JAPAN	ABSTRACT

Examiner <i>Jack Berman</i>	Date Considered <i>5/29/03</i>
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	Applicant: Mamoru NAKASUJI et al.	
	Filing Date: June 27, 2001	Group Art Unit:







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<i>JPB</i>	AW	6,125,522	Nakasuji	10/03/00		11/12/96
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<i>JPB</i>	BJ	✓ Low Voltage and high speed operating electrostatic wafer chuck using sputtered tantalum oxide membrane, Mamoru Nakasuji et al., J. Vac. Sci. Technol. A 12(5), Sep/Oct 1994, American Vacuum Society pp. 2834-2839.
<i>JPB</i>	BK	✓ High -Emittance and Low-Brightness Electron Gun for Reducing-Image Projection System: Computer Simulation, Mamoru Nakasuji et al., Jpn. J. Appl. Phys. Vol. 36 (1997) pp.2404-2408.
<i>JPB</i>	BL	✓ H. Hayashi, et al., LSI Testing Symposium 1998, Minutes of the meeting, P160 (1998) (partial translation)
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	Applicant: Mamoru NAKASUJI et al.	
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Examiner <i>Jack Berman</i>	Date Considered <i>8/29/03</i>	

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**INFORMATION  
DISCLOSURE  
CITATION**  
PTO-1449

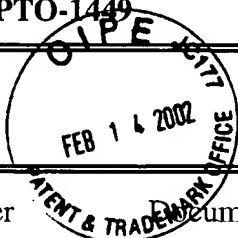
Atty. Docket No. 010816

Serial No. 09/891,612

Applicant(s): NAKASUJI, et al.

Filing Date: June 27, 2001

Group Art Unit: 2877



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	AC					

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